

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:
Christopher W. Hill

Serial No.:

Filed: May 19, 2004

For: SILICON NANOCRYSTAL CAPACITOR AND
PROCESS FOR FORMING SAME

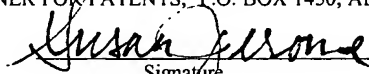
§
§ Group Art Unit:
§
§ Examiner:
§
§ Atty. Docket: 2001-0827.01/US
§
§ Paper No.
§

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

"EXPRESS MAIL" MAILING LABEL NUMBER: **ET658403000US**
DATE OF DEPOSIT **May 19, 2004**
I HEREBY CERTIFY THAT THIS PAPER IS BEING DEPOSITED WITH
THE UNITED STATES POSTAL SERVICE "EXPRESS MAIL POST
OFFICE TO ADDRESSEE" SERVICE UNDER 37 C.F.R. § 1.10 ON THE
DATE INDICATED ABOVE AND IS ADDRESSED TO
COMMISSIONER FOR PATENTS, P.O. BOX 1450, ALEXANDRIA, VA
22313-1450.


Signature

In compliance with the duty of disclosure under 37 C.F.R. § 1.56, Applicant respectfully requests that this Information Disclosure Statement be entered and that the references listed on the attached Form PTO-1449 be considered by the Examiner and made of record. Copies of the listed references are enclosed for the convenience of the Examiner.

In accordance with 37 C.F.R. § 1.97(g), this Information Disclosure Statement is not to be construed as a representation that a search has been made or that no other possible material information as defined in 37 C.F.R. § 1.56(a) exists.

The following references are submitted for the Examiner's review:

Other References

"Synthese and characterization of aerosol silicon nanocrystal nonvolatile floating-gate memory device", M.L. Ostraat et al., Applied Physics Letters, Volume 79, Number 3, July 16, 2001, pages 433-435.

"Ultraclean Two-Stage Aerosol Reactor for Production of Oxide-Passivated Silicon Nanoparticles for Novel Memory Devices", Michele L. Ostraat et al., Journal of The Electrochemical Society, 148 (5), Pages G265-G270

As this information is being submitted within three months of the date of filing of the application, Applicant understands that no fee or certification is required for the submission and consideration of this information at this time.

If there are any matters which may be resolved or clarified through telephone interview, the Examiner is respectfully requested to contact Applicant's undersigned agent at the number indicated.

* * * *

A Form PTO-1449 is enclosed herewith.

Date: 05/19/2004

Respectfully submitted,



David J. Paul
Reg. No. 34,692
Micron Technology, Inc.
8000 S. Federal Way
Boise, ID 83706-9632
(208) 368-4515
AGENT FOR APPLICANT

FORM: PTO-1449 (REV: 7-80)	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	Atty Docket No: 2001-0827.01	Serial No:
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (37 CFR 1.98(b)) <i>(use several sheets if necessary)</i>		Applicant: Christopher W. Hill	
		Filing Date: May 19, 2004	Group:

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	
	AA					
	AB					
	AC					
	AD					
	AE					
	AF					
	AG					
	AH					
	AI					
	AJ					
	AK					
	AL					
	AM					
	AN					

FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation	
	AO					Yes	No
	AP					<input type="checkbox"/>	<input type="checkbox"/>
	AQ					<input type="checkbox"/>	<input type="checkbox"/>

Initial

OTHER ART (including author, title, date, pertinent pages, etc.)

	AR		"Synthese and characterization of aerosol silicon nanocrystal nonvolatile floating-gate memory device", M.L. Ostraat et al., Applied Physics Letters, Volume 79, Number 3, July 16, 2001, pages 433-435.
	AS		"Ultraclean Two-Stage Aerosol Reactor for Production of Oxide-Passivated Silicon Nanoparticles for Novel Memory Devices", Michele L. Ostraat et al., Journal of The Electrochemical Society, 148 (5), Pages G265-G270

Examiner:	Date Considered:
-----------	------------------

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication with applicant.